



RE PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE AUG 30 2001

TECHNOLOGY CENTER 2800

In re Application of:

Pan et al.

Serial No.: 09/073,494

Filed: May 6, 1998

For: TECHNIQUE FOR ELIMINATION OF
PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Examiner: H. Vu

Group Art Unit: 2811

Attorney Docket No.: 2915.1US (96-149.1)

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Person making Deposit: Jared Turner

21/F
F Jones

PRELIMINARY AMENDMENT

Box RCE

Hon. Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination of the claims on the merits in the above-identified application, please amend this application as follows:

IN THE CLAIMS:

Please note that all claims currently pending and under consideration in the referenced application are shown below, in clean form, for clarity. A marked up version of the claims with amendments is attached hereto.